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First Named Inventor: Weidong Yang

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Examiner Name: Unknown

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## INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(Use several sheets if necessary)



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*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	1.	5,214,492	25-May-93	LoBianco et al.	356	400	8/2/1991
	2.	5,216,257	Jun. 1, 1993	Brueck et al.	250	548	7/9/1990
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	5.	5,805,290	Sep. 8, 1998	Ausschnitt et al.	356	401	5/2/1996
	6.	5,969,819	Oct. 19, 1999	Wang	356	371	6/5/1997
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	8.	6,084,712	Jul. 4, 2000	Harding	356	618	11/3/1998
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	21. WO 02/065545 A2	Aug. 22, 2002	PCT	H01L	21/66	2/12/2001	
	22. WO 02/069390 A2	Sep. 6, 2002	PCT	H01L	21/66	2/27/2001	

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\*EXAMINER: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.



24.	WO 02/084213 A1	Oct. 24, 2002	PCT	G01B	Nov-00	4/10/2001	
25.	WO 02/25723 A2	Mar. 28, 2002	PCT	H01L	21/66	9/19/2000	
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26.	Bischoff, J. et al., "Light Diffraction Based Overlay Measurement" <i>Proceedings of SPIE</i> , Vol. 4344 (2001) Pages 222-233
27.	Michaelis, A. et al., "Spectroscopic Anisotropy Micro-Ellipsometry (SAME) for determination of lateral and vertical dimensions of sub-micron lithographic structures" IEEE Catalog Number 99TH8453 (1999) Pages 131-134
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